

MANAGEMENT SYSTEM, METHOD, AND COMPUTER PROGRAM FOR SEMICONDUCTOR FABRICATION APPARATUS

ABSTRACT

In a semiconductor fabrication apparatus composed of a plurality of components, such as fluid control devices, a manager is to be enabled to identify components by intuition. Information on the identified component is to be provided to the manager in an easy-to-understand manner. In a system in which a manager terminal 3 and an information processor 2 are communicably configured via networks NW1 and NW2, the manager terminal 3 receives component information on a semiconductor fabrication apparatus 1 from the information processor 2. Upon the identification of the position of a component constituting the semiconductor fabrication apparatus 1 on the captured image of the semiconductor fabrication apparatus 1 using an identification processing unit 32, a compositing processing unit 33 creates a composite image in which component information is composited with the captured image at the position of the component identified, and an image display unit 34 displays the composite image. On the other hand, the information processor 2 makes reference to the component information storage unit 2A to extract the component information using an extraction processing unit 21, and transmits the component information to the manager terminal 3.

FIG. 3